

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMJP.128AUS	APPLICATION NO. <small>-Unknown</small> <u>10/618, 950</u>
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>(USE SEVERAL SHEETS IF NECESSARY)</small>	APPLICANT Akira Shimizu, et al.	
	FILING DATE Herewith	GROUP <small>Unknown</small> <u>1763</u>

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
RR	1. 6-316765	11/15/94	Japan (Pat. No. 3112721 Issued 9/22/00)			abstract	
	2. 2000-199067	07/18/00	Japan			abstract	
	3. 2001-11634	01/16/01	Japan			abstract	
✓	4. 2001-148347	05/29/01	Japan			abstract	

**EXAMINER
INITIAL**

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

- John J. Sullivan, et al. Optimization of the Copper Precursor Delivery for CVD Deposition Process, Technical Report, MKS Instruments, Inc. Andover, MA 01810, pages 1-6
Direct Liquid Injection System, Japan MSK, Nikko No. 97, 10.08.200.

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EXAMINER	DATE CONSIDERED	<i>Brad Zonges</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED. WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPPB 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.		